

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:) **HAND-DELIVERY**
Ge XU et al.) **CP 3 - 8TH FLOOR**
Application No.: 09/863,338) Group Art Unit: 1763
Filed: May 24, 2001) Examiner: S. MacArthur
For: CVD APPARATUS) Confirmation No. 1018
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PRELIMINARY AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

Preliminary to examination, kindly enter new claims 25-31 as follows.

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25 (new) A CVD apparatus as stated in claim 1, further comprising an RF power supply
for feeding a cleaning RF power and a switch for connecting the partitioning wall section
to the RF power supply with suitable timing so as to produce a cleaning plasma in the film
deposition process space.

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26. (new) A CVD apparatus as stated in claim 5, wherein the connecting means includes
a switch which selectively connects the partitioning wall to the RF power supply for
feeding a cleaning RF power and to a ground for cleaning using the RF power supplied to
the radio-frequency electrode in the first chamber.